

METHOD FOR MANUFACTURING VARISTOR

TECHNICAL FIELD

The present invention relates to a method for manufacturing a
5 varistor.

BACKGROUND ART

Conventionally, after forming electrodes on the surface of a varistor
element mainly composed of ZnO, a high resistance layer made of glass was
10 formed on the surface of the varistor element, and the surface of the
electrodes was plated to obtain a varistor.

However, the high resistance layer made of glass could not be formed
selectively on the surface of the varistor element alone, and it was hard to
form in a uniform thickness. Accordingly, when plating, plating flow
15 occurred to cause shorting, or moisture invaded into the varistor element to
deteriorate the electric characteristic of the varistor.

DISCLOSURE OF THE INVENTION

It is hence an object of the invention to present a method for
20 manufacturing a varistor having a high plating resistance and a high
moisture resistance by selectively forming a compact high-resistance layer
with a uniform thickness on the surface of a varistor element.

To achieve the object, a method for manufacturing a varistor of the
invention comprises a first step of obtaining a varistor element by forming a
25 material mainly composed of ZnO, a second step of forming at least two first

electrodes at a specific spacing on the surface of the varistor element, a third step of applying a first heat treatment to the varistor element, and a fourth step of applying a second heat treatment after disposing Si powder on the surface of the varistor element.

5 According to this method, since a dense high-resistance layer having a uniform thickness is formed, a varistor excellent in a moisture resistance and a plating resistance can be obtained.

BRIEF DESCRIPTION OF THE DRAWINGS

10 Fig. 1 is a sectional view of a varistor in an embodiment of the invention, and Fig. 2 is an explanatory diagram of burning process in an embodiment of the invention.

BEST MODE FOR CARRYING OUT THE INVENTION

15 In Fig. 1, plural inner electrodes 2 mainly composed of Ag are provided inside a varistor element 1. These inner electrodes 2 are alternately drawn out to both ends of the varistor element 1, and are electrically connected to outer electrodes 3 individually at the both ends. Ceramic sheets 1a laminated between inner electrodes 2 and at the outer side
20 thereof are mainly composed of ZnO, and contain also Bi_2O_3 , Co_2O_3 , MnO_2 , Sb_2O_3 , and others as a subsidiary component. Reference numerals 4a, 4b are high-resistance layers formed when burned together with SiO_2 or a mixture containing SiO_2 as a principal component. Figure 2 shows a state of heat treatment that the element 1 is heated in an alumina crucible 6
25 together with SiO_2 powder or a powder mixture containing SiO_2 as a

principal component and at least one selected from the group of Fe_2O_3 , Sb_2O_3 , TiO_2 , Al_2O_3 , Bi_2O_3 , B_2O_3 , PbO , Na_2CO_3 , K_2CO_3 , MgO , CaCO_3 and AgO as a subsidiary component (hereinafter called SiO_2 or mixture 5), when forming the high-resistance layers 4a, 4b on the surface of the varistor element 1.

A method for manufacturing a varistor of this embodiment is described below.

First, ceramic sheets 1a were obtained by mixing a material mainly composed of zinc oxide, a plasticizer, a binder, and others, grinding the mixture, forming the ground mixture into slurry, and forming the slurry into sheets. Then, these ceramic sheets 1a and inner electrodes 2 mainly composed of silver were alternately laminated, and the laminated body was cut into a predetermined size so that the inner electrodes 2 may be drawn out to the corresponding end surfaces alternately in order to obtain a varistor element 1. Next, the varistor element 1 was heated for a time of 5 minutes to 10 hours at a temperature of 100 to 300°C to remove the plasticizer from the varistor element 1, and the surface of the varistor element 1 was chamfered.

Consequently, both end surfaces of the varistor element 1 were coated with an Ag electrode paste which became to outer electrodes 3, and the varistor element 1 was sintered by heat treatment for a time of 5 minutes to 10 hours at a temperature of 600 to 950°C.

And then, the varistor element 1 was buried in SiO_2 or mixture 5 and heated for a time of 5 minutes to 10 hours at a temperature of 600 to 950°C in air or oxygen atmosphere, by using an alumina crucible 6 as shown in Fig.

2. By this heat treatment, ZnO which is a principal component of the varistor element 1 and SiO_2 react each other, and a high-resistance layer 4a mainly composed of Zn_2SiO_4 is formed on the surface of the varistor element 1. Incidentally, when Bi_2O_3 is added as a subsidiary component to the varistor element 1, Bi_2O_3 reacts with ZnO and SiO_2 to promote formation of Zn_2SiO_4 , and also a high-resistance layer 4b mainly composed of $\text{Bi}_4(\text{SiO}_4)_3$ is formed between the high-resistance layer 4a and the surface of the varistor element 1. Since they react and are formed in the portions not expressing the electric characteristic of varistor, they have no adverse effects on the electric characteristic of varistor, so that an excellent varistor extremely superior in a plating resistance and a moisture resistance is obtained.

What is important herein is that, as shown in Fig. 2, the entire outer surface of individual varistor elements 1 should be buried so as to contact with SiO_2 or mixture 5. For this purpose, SiO_2 or mixture 5 is spread in the alumina crucible 6 in a specified thickness, and a specified number of varistor elements 1 are arranged thereon so as not to contact with each other. And then, SiO_2 or mixture 5 is put over in this state, and heat treatment is applied. Depending on the composition of mixture 5, however, mixture 5 may contact on the outer electrode 3 due to anchor effect, and in such a case it is necessary to keep conduction by removing mixture 5 on the outer electrode 3 by grinding or the like. If the anchor effect is too large to be removed by grinding or the like, or if the high-resistance layers 4a, 4b on the surface of the varistor element 1 are removed by grinding, a further outer electrode past may be applied and baked on the outer electrode 3 to form the outer electrodes to keep conduction.

Afterwards, electrolytic Ni plating and electrolytic solder plating were applied on the surface of the outer electrodes 3, and a varistor was obtained. The plating thickness of the obtained varistor was $2\mu\text{m}$ in Ni plating and $2\mu\text{m}$ in solder plating.

5 Results of plating resistance of the varistors are shown in Table 1.

As shown in Table 1, when the varistor element 1 not including high resistance-layers 4a, 4b is plated, the surface of the varistor element 1 other than the outer electrodes 3 is also plated. When Fe_2O_3 , Sb_2O_3 , TiO_2 , Al_2O_3 , Bi_2O_3 , B_2O_3 or glass frit which is a subsidiary component is added to SiO_2 ,
10 instead of SiO_2 alone, flow of plating is further decreased, and more uniform high-resistance layers 4a, 4b seem to be formed.

Table 2 shows the voltage ratio ($V_{1\text{mA}}/V_{10\mu\text{A}}$) of the varistors after burning in SiO_2 or mixture 5.

As shown in Table 2, the varistor including the mixture of SiO_2 with
15 PbO , Na_2CO_3 , K_2CO_3 , MgO , CaCO_3 and Ag_2O is smaller in the voltage ratio than the varistor including SiO_2 powder alone, and is more excellent in the nonlinearity of low current region. This is considered because the addition of such additives contributes to stabilization of the grain boundary area that seems to determine the nonlinearity.

20 In the varistor of the embodiment, while resistance of the surface is heightened, it is also enhanced in density, and therefore it simultaneously brings about the effect of prevention of invasion of plating solution at the time of plating.

Table 1

	Prior art	Embodiment							
Mixed powder	No coating	SiO ₂	SiO ₂ :Fe ₂ O ₃ =95:5(wt%)	SiO ₂ :Sb ₂ O ₃ =95:5(wt%)	SiO ₂ :TiO ₂ =95:5(wt%)	SiO ₂ :Al ₂ O ₃ =95:5(wt%)	SiO ₂ :Bi ₂ O ₃ =95:5(wt%)	SiO ₂ :B ₂ O ₃ =99:1(wt%)	SiO ₂ :glass frit =95:5(wt%)
Ratio of flow of plating	50/50	2/50	0/50	0/50	0/50	0/50	0/50	0/50	0/50

Ratio = Number of samples causing flow of plating / total number of samples

Table 2

Mixed powder	SiO ₂	SiO ₂ :PbO =95:5(wt%)	SiO ₂ :Na ₂ CO ₃ =95:5(wt%)	SiO ₂ :K ₂ CO ₃ =95:5(wt%)	SiO ₂ :MgO =95:5(wt%)	SiO ₂ :CaCO ₃ =95:5(wt%)	SiO ₂ :Ag ₂ O =95:5(wt%)
V _{1mA} /V _{10μA}	1.23	1.11	1.1	1.12	1.12	1.13	1.12

Important points in this invention are described below.

(1) When burying a varistor element 1 in SiO_2 or mixture 5, although high-resistance layers 4a, 4b are formed only by burying as shown in Fig. 2, considering the reactivity, it is more effective to strengthen the adhesion between SiO_2 or mixture 5 with a varistor element 1 by applying pressure by putting a weight or the like on mixture 5 in Fig. 2.

(2) In heat treatment for forming high-resistance layers 4a, 4b, by rotating by putting a specified number of varistor elements 1 and SiO_2 or mixture 5 into a sleeve such as a cylindrical piece, more uniform high-resistance layers 4a, 4b can be formed. Besides, by heating while rotating, as compared with the case of using the crucible 6, not only high-resistance layers 4a, 4b can be formed by a small amount of SiO_2 or mixture 5, but also temperature fluctuations of the varistor element 1 are small, so that a varistor having small fluctuations of varistor characteristics such as a varistor voltage can be obtained.

(3) After immersing a varistor element 1 in a liquid containing at least one organic metal compound selected from the group consisting of organic metal compounds of Si, Pb, Fe, Sb, Ti, Al, B, Bi, Ag, alkaline metal, and alkaline earth metal, by burying the varistor element 1 in SiO_2 or mixture 5 and heating, dense high-resistance layers 4a, 4b having much uniform thickness can be formed.

(4) In the embodiment, high-resistance layers 4a, 4b are formed by heating in SiO_2 or mixture 5, after heating and sintering the varistor element 1. This is because, considering the stability of electrical characteristics and ceramic characteristics of the varistor, better results are

obtained when sintering reaction and high-resistance layer forming reaction of the varistor element 1 are done separately. If, however, the sintering reaction and high-resistance layer forming reaction of the varistor element 1 are done simultaneously, the high resistance layers 4a, 4b can be
5 formed. At this time, whether the varistor element 1 is formed before or after forming the outer electrode 3, it is important that the outer electrode 3 should be formed so as to conduct with outside during use.

(5) In this embodiment, SiO_2 and the additives in mixture 5 are added in oxide form, but as far as becoming an oxide in the reaction
10 temperature range (600 to 950°C), not limited to oxide, but any compound may be used.

(6) In mixture 5, by defining the principal component SiO_2 at 80 wt.% or more, high-resistance layers 4a, 4b can be formed easily.

(7) By adding a compound of Fe, Sb, Ti, Al, Bi or B, or glass frit to
15 mixture 5 mainly composed of SiO_2 , a tendency of higher resistance is noted, and by adding a compound of Ag, Pb, alkaline metal or alkaline earth metal, enhancement of nonlinearity of varistor characteristic is observed.

(8) In the embodiment, only one of oxides of Fe, Sb, Ti, Al, Bi, B, Ag, Pb, alkaline metal or alkaline earth metal, or glass frit is added to mixture 5
20 mainly composed of SiO_2 , but if two or more compounds thereof are added, the same effects are obtained.

(9) The glass frit composed of 60 wt% of Bi_2O_3 , 20wt% of B_2O_3 , 10wt% of SiO_2 , and 10wt% of Ag_2O is used in the embodiment, and if glass frit containing B is used, it is easy to form high-resistance layers 4a, 4b, since
25 the softening point is low.

(10) If attempted to form uniform high-resistance layers 4a, 4b, it is preferred to make uniform the particle size of SiO_2 or mixture 5 as far as possible.

(11) The embodiment relates to the laminate type varistor, but same effects are obtained in a varistor in disk shape or other shape.

INDUSTRIAL APPLICABILITY

According to the invention, high-resistance layers of Zn-Si-O system or Bi-Si-O system mainly composed of Zn_2SiO_4 or $\text{Bi}_4(\text{SiO}_4)_3$ are formed in the surface of a varistor element not covered with electrodes. Since these high-resistance layers are dense and uniform in thickness, they prevent invasion of undesired moisture or the like from invading into the varistor element, so that the varistor characteristics may not deteriorate. Moreover, it is also effective to prevent occurrence of defect such as short circuit due to plating of other portions than the electrode area of the surface of the varistor element at the time of plating. Still more, in the case of a laminate varistor, the size can be reduced, since the thickness of the reactive layer can be made thinner than before.



CLAIMS

1. A method for manufacturing a varistor comprising a first step of obtaining a varistor element by forming a material mainly composed of ZnO, a second step of forming at least two first electrodes at a specific spacing on
5 a surface of the varistor element, a third step of applying a first heat treatment to the varistor element, and a fourth step of applying a second heat treatment after disposing Si powder on a surface of the varistor element.
2. The method for manufacturing a varistor of claim 1, wherein the
10 fourth step is to heat while rotating the varistor element and the Si powder.
3. The method for manufacturing a varistor of claim 1, wherein the Si powder in the fourth step is replaced by a mixture of a principal component of Si compound and a subsidiary component of at least one selected from the group consisting of Pb compound, Fe compound, Sb
15 compound, Ti compound, Al compound, B compound, Bi compound, Ag compound, alkaline metal compound, alkaline earth metal compound, and glass frit (except when using Pb compound, alkaline metal compound, or alkaline earth metal compound is used alone).
4. The method for manufacturing a varistor of claim 3, wherein the
20 heat treatment in the fourth step is performed while rotating the varistor element and the mixture.
5. The method for manufacturing a varistor of claim 1, wherein a second electrode is formed on each of the at least two first electrodes after the fourth step.
- 25 6. The method for manufacturing a varistor of claim 1, wherein the





varistor element is immersed in a liquid containing at least one organic metal compound selected from the group consisting of organic metal compounds of Si, Pb, Fe, Sb, Ti, Al, B, Bi, Ag, alkaline metal, and alkaline earth metal, after the third step.

5 7. A method for manufacturing a varistor comprising a first step of obtaining a varistor element by forming a material mainly composed of ZnO, a second step of forming at least two first electrodes at a specific spacing on a surface of the varistor element, and a third step of applying a heat treatment after disposing a mixture of a principal component of Si
10 compound and a subsidiary component of at least one selected from the group consisting of Pb compound, Fe compound, Sb compound, Ti compound, Al compound, alkaline metal compound, alkaline earth metal compound, and glass frit (except when using Si compound, Pb compound, alkaline metal compound, or alkaline earth metal compound is used alone) on a
15 surface of the varistor element.

8. The method for manufacturing a varistor of claim 7, wherein a second electrode is formed on each of the at least two first electrodes after the third step.

9. The method for manufacturing a varistor of claim 7, wherein the
20 varistor element is immersed in a liquid containing at least one organic metal compound selected from the group consisting of organic metal compounds of Si, Pb, Fe, Sb, Ti, Al, B, Bi, Ag, alkaline metal, and alkaline earth metal, after the second step.

10. The method for manufacturing a varistor of claim 7, wherein the
25 heat treatment in the third step is performed while rotating the varistor



element and the mixture.

11. The method for manufacturing a varistor comprising a first step of obtaining a varistor element by forming a material mainly composed of ZnO, a second step of applying a heat treatment after disposing a mixture of a principal component of Si compound and a subsidiary component of at least one selected from the group consisting of Pb compound, Fe compound, Sb compound, Ti compound, Al compound, B compound, Bi compound, Ag compound, alkaline metal compound, alkaline earth metal compound, and glass frit (except when using Si compound, Pb compound, alkaline metal compound, or alkaline earth metal compound is used alone) on a surface of the varistor element, and a third step of forming at least two electrodes on a surface of the varistor element.

12. The method for manufacturing a varistor of claim 11, wherein the varistor element is heated between the first step and second step.

13. The method for manufacturing a varistor of claim 11, wherein the varistor element is immersed in a liquid containing at least one metal compound selected from the group consisting of organic metal compounds of Si, Pb, Fe, Sb, Ti, Al, B, Bi, Ag, alkaline metal, and alkaline earth metal, before the second step.

14. The method for manufacturing a varistor of claim 11, wherein the heat treatment in the second step is performed while rotating the varistor element and the mixture.